

Notice of References Cited	Application/Control No. 10/729,458	Applicant(s)/Patent Under Reexamination CHIU ET AL.	
	Examiner Mahmoud Dahimene	Art Unit 1765	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-2005/0093063	05-2005	Lim et al.	257/347
*	B	US-6,784,060	08-2004	Ryoo, Doo Yeol	438/275
*	C	US-2005/0158671	07-2005	Shimizu et al.	430/329
*	D	US-2002/0173156	11-2002	Yates et al.	438/695
*	E	US-6,551,884	04-2003	Masuoka, Sadaaki	438/275
*	F	US-6,286,231	09-2001	Bergman et al.	34/410
*	G	US-2002/0166572	11-2002	Chen, Chung-Tai	134/3
*	H	US-2003/0106572	06-2003	Nishiki et al.	134/26
*	I	US-6,286,231	09-2001	Bergman et al.	34/410
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	S. Wolf and R.N. Ttauber, Silicon Processing for the VLSI Era, Volume 1- Process Technology, Lattice Press, 1986, pages 532, 215, 518.
	V	S. Wolf , Silicon Processing for the VLSI Era, Volume 2- Process integration, Lattice Press, 1990, pages 318, 398
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.